

Electronic Patent Application Fee Transmittal

Application Number:	09546174			
Filing Date:	11-Apr-2000			
Title of Invention:	HIGH DENSITY PLASMA CHEMICAL VAPOR DEPOSITION PROCESS			
First Named Inventor/Applicant Name:	Chih-Chien Liu			
Filer:	William H. Wright			
Attorney Docket Number:	JIA 462C1			
Filed as Large Entity				
Utility under 35 USC 111(a) Filing Fees				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
Claims:				
Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				
Filing a brief in support of an appeal	1402	1	510	510
Post-Allowance-and-Post-Issuance:				
Extension-of-Time:				

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Extension - 1 month with \$0 paid	1251	1	120	120
Miscellaneous:				
Total in USD (\$)				630